



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No.09/360,292
Filing DateJuly 22, 1999
Inventor.....Sujit Sharan et al.
Assignee.....Micron Technology, Inc.
Group Art Unit.....1765
ExaminerAhmed, Shamim
Attorney's Docket No.MI22-1106
Title: Plasma Etching Process

RESPONSE TO NOVEMBER 15, 2004 OFFICE ACTION

To: Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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AMENDMENTS

Introductory Comments

In response to the Office Action dated November 15, 2004, applicant amends and remarks as follows.